IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of:		
	Shinichiro Nohdo	Group Art Unit: 2877
Application No. 10/812,602		Confirmation No.: 3173
Filed:	March 30, 2004)) Examiner: Rebecca Slomski))
For:	WAFER, EXPOSURE MASK, METHOD OF DETECTING MARK AND METHOD OF EXPOSURE	

MAIL STOP AMENDMENT Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

RESPONSE TO APRIL 24, 2007 OFFICE ACTION

Dear Sir:

This Amendment is submitted in response to the Office Action mailed April 24, 2007.

Applicant respectfully requests reconsideration of the application in view of this amendment and remarks herein.